

What is claimed is:

1. A chuck equipment comprising  
a plate-shaped base,  
a first electrode to which a first voltage is applied,  
5 and  
a second electrode to which a second voltage  
different from the first voltage in magnitude is applied,  
the first and second electrodes being insulated from each  
other and arranged on a surface of said base.
- 10 2. The chuck equipment according to claim 1, wherein  
said surfaces of said first and second electrodes are  
exposed.
3. The chuck equipment according to claim 2, wherein  
the chuck equipment is constructed in such a manner that a  
15 substrate is placed on the surface of said chuck equipment  
on which said first and second electrodes are arranged to  
cause said substrate to be brought into contact with said  
first and second electrodes.
4. The chuck equipment according to claim 2, wherein  
20 the surface of said base is flush with the surfaces of said  
first and second electrodes.
5. The chuck equipment according to claim 2, wherein  
an insulating convexity portion is arranged between said  
first and second electrodes.
- 25 6. The chuck equipment according to claim 2, wherein



electric field of  $1.0 \times 10^6$  V/m or greater between said first and second electrodes.

14. The vacuum processing apparatus according to claim 13, wherein a protective plate is arranged around said chuck equipment, and the vacuum processing apparatus is constructed in such a manner that a substrate is placed on said chuck equipment to cause said substrate to be accommodated in said protective plate.